

S. R. J. BRUECK

Professional Employment History:

University of New Mexico	Director, Center for High Technology Materials	1986 - present
University of New Mexico	Distinguished Professor of Electrical and Computer Engr. Distinguished Professor of Physics and Astronomy	2006 - present
University of New Mexico	Professor of Electrical and Computer Engineering, Professor of Physics and Astronomy	1985 - 2006
M.I.T. Lincoln Laboratory	Research Staff Member, Quantum Electronics Group	1973 - 1985
M.I.T. Lincoln Laboratory	Postdoctoral Appointment, Quantum Electronics Group	1971 - 1973
M.I.T. Lincoln Laboratory	Research Assistant, Applied Physics Group	1967 - 1971
Bell Telephone Laboratories	Member Technical Staff	1967 summer
M.I.T.	Research Assistant, Research Laboratory of Electronics	1965 - 1967

Boards of Directors:

LightPath, Inc.	2001 – present
Science and Technology Corporation @ UNM	2001 – 2005

Education:

Doctor of Philosophy in Electrical Engineering Massachusetts Institute of Technology Thesis: <i>Spontaneous and Stimulated Spin-Flip Raman Scattering in InSb</i>	1971
Master of Science in Electrical Engineering Massachusetts Institute of Technology Thesis: <i>Microwave Acoustic Instabilities in Semiconductors in a Magnetic Field</i>	1967
Bachelor of Science in Electrical Engineering Columbia University	1965

Research Accomplishments:

- First demonstration of CW stimulated Raman scattering (spin-flip scattering in InSb)
- Physics of spontaneous and stimulated spin-flip Raman scattering.
- Vibrational energy transfer in cryogenic liquids.
- Discovery of radiatively limited lifetime of 1 sec for vibrational mode of liquid N₂; $10^{12} \times$ the vibrational dephasing time.
- Nonlinear optics of cryogenic liquids (third harmonic generation, two-photon linewidths, Kerr switching).
- Importance of vibration-rotation coupling in determining the two-photon Q-branch (Raman) lineshape in liquids.
- Raman scattering studies of stress in silicon-on-insulator materials.
- Development of surface-acoustic wave spectroscopy as an ultrasensitive technique for the measurement of submonolayer absorbate coverages.
- Record sensitivity for absorbance measurements of $\alpha L \sim 10^{-9}$.
- Reactive-ion etch induced fluorescence for the depth profiling of impurities (e. g. Na) in SiO₂
- Laser-induced fluorescence studies of radical species in plasma-etching of semiconductor materials
- Stimulated surface-plasma wave scattering leading to surface ripples in laser-material interactions.
- Enhanced coupling of light to nanostructures on the scale of the optical wavelength.
- Resonant-periodic-gain surface-emitting lasers.
- High-speed metal-semiconductor-metal (Ni-Si-Ni) photodetectors
- Ultra-high resolution MSM position sensors (< 4 nm precision).

- Discovery of large $\chi^{(2)}$ nonlinearity (~ 1 pm/V) in silica glass.
- Electrooptic effect in bulk, thin film and fiber geometries.
- Multiple-exposure interferometric lithography for extreme sub-micrometer lithography.
- Fabrication technology for large area Si quantum walls and wires; studies of optical properties - Raman scattering and photoluminescence.
- Moiré and speckle techniques for noncontact temperature measurement with 1°C resolution.
- Sub-feature speckle interferometry, a new technique for non-contact, sub- λ position measurement.
- Imaging interferometric lithography marrying optical and interferometric approaches to print arbitrary structures to ~ 70 nm scales.
- Imaging interferometric lithography – extending optical lithography to fundamental linear systems limits.
- Nonlinear interferometric lithography – use of processing nonlinearities to exceed the linear systems limits of optics.
- Nanoheteroepitaxy – growth of heterostructure materials (GaAs and GaN on Si) using nanoscale seeds.
- Nanoscale MBE growth – first demonstration of selective growth in MBE; growth of single InAs quantum dots; combination of lithographic and self-assembly to grow 1D rows of quantum dots.
- Analytic calculation of dipole radiation in confined structures.
- First infrared magnetic resonance structures.
- Integrated nanofluidic chip: mm's to nm's and demonstrations of dye and biomolecular separations.
- First experimental realization of near-IR negative index metamaterials.
- $> \text{Tb/s}$ metamaterial modulators.
- Imaging interferometric microscopy to extend optical microscopy to the nanoscale.
- Broadly tunable, optically pumped infrared lasers based on chirped DFB gratings.

Current Research (May-13):

Interferometric lithography and microscopy is increasing in importance to both Si integrated circuit manufacturing and display research communities. Over the longer term, we are exploring the application of interferometry to the high-resolution that will be necessary for future generations of integrated circuits, by developing techniques to introduce the necessary pattern flexibility. We have demonstrated imaging-interferometric lithography with the potential to extend the resolution of optics to $\lambda/3n$ (45 nm at a 193-nm exposure wavelength). Nonlinear processes allow extension of these limits by integer divisors, e.g. to 22 nm for a doubling process and 12 nm for a tripling process. Other, fundamental-research-oriented applications of interferometric lithography include: studies of optical emission from Si nanostructures (< 10 nm feature sizes); nanoheteroepitaxy - the use of interferometrically defined nanostructures as a substrate for epitaxial growth that alleviates many of the limitations imposed on growth of heterostructure materials by differing lattice constants and thermal expansion coefficients; studies of electromagnetic interactions with materials structured at the wavelength scale; and new electronic devices such as transverse resonant tunneling diodes enabled by this new lithographic capability. Recently, we have extended these ideas to microscopy, where they are essentially a synthetic aperture approach, demonstrating a resolution of < 150 nm ($\lambda/4.2$) with a 633 nm source and a modest 0.4 NA objective. This is extensible to $\sim \lambda/15$, putting optical microscopy well into the nanoscale regime.

Nanoscale epitaxial growth is a new regime in epitaxial growth wherein the growth seed structures are fabricated using interferometric lithography (or other large-area nanoscale lithography). This allows the observation of many new crystal growth phenomena. Previous work on patterned growth has been restricted to much large scales; the important physical scales are of the order of surface diffusion lengths which are typically submicrometer, and are uniquely accessible by the lithographic techniques we have been developing. Important directions include nanoheteroepitaxy for the growth of materials with signifi-

cant lattice and thermal expansion mismatches and nanoscale MBE growth for investigation of the interplay of patterning and self-assembly, particularly for novel structures such as quantum dots.

Nanophotonics is another emerging area of great potential importance. Our group has been a leader in developing large-area nanoscale patterning for these applications. Important firsts include: first mid-IR negative permeability material; first near-IR negative-index material; first demonstration of enhanced transmission through metallic coaxial array structures in the MWIR and NIR. Recently, we have demonstrated a high speed (< 600 fs) all-optical modulator based on a fishnet metamaterial with a path length on only ~ 100 nm.

Administrative Experience:

Technical leadership and administrative responsibilities have been major aspects of my position as director of the Center for High Technology Materials. CHTM was initiated by the state of New Mexico with goals of establishing a major research center, encouraging interactions with federal laboratories and industry, and contributing to the economic development of New Mexico. During my tenure as director, CHTM has developed to a well-established, internationally recognized center for photonics and nanoelectronics.

Theses Supervised:

M. Y. A. Raja	<i>Wavelength-Resonant Surface Emitting Semiconductor Laser</i>	PhD	Physics	1988
Saleem H. Zaidi	<i>An Investigation of Holographic Grating Fabrication and Optical Coupling to Surface Plasma Waves</i>	PhD	Physics	1989
Schubert Soares	<i>High-Speed Ultraviolet Photomixers</i>	PhD	ECE	1989
Billy Wayne Mullins	<i>Heterodyne Characterization of High-Speed Photomixers for the Ultraviolet</i>	PhD	Physics	1989
Yue-Chue Fong	<i>Confocal Photoluminescence - Theory and Applications</i>	PhD	ECE	1993
Ashwani Sharma	<i>Extended-Wavelength Si MSM Photodetectors</i>	MS	ECE	1994
David Burckel	<i>Sub-Feature Speckle Interferometry</i>	MS	ECE	1995
Congzhong Huang	<i>Noncontact, Optical Diffraction Measurement of Semiconductor Temperature</i>	MS	ECE	1995
Richard A. Myers	<i>Large Second-Order Nonlinearity in Amorphous SiO₂ Using Temperature/Electric-Field Poling</i>	PhD	Physics	1995
An-Shyang Chu	<i>Si Quantum Walls: Fabrication and Optical Characterization</i>	PhD	Physics	1996
John V. Sandusky	<i>Microcavity Effects in an External Cavity Surface-Emitting Laser</i>	PhD	Physics	1997
Kristen A. M. Scott	<i>Silicon Metal-Semiconductor-Metal Photodetectors: Ion-Implanted High-Speed Near-Infrared Photodiodes and Position-Sensitive Photodetectors</i>	PhD	Physics	1997
Xiancun Tony Long	<i>Physics and Device Applications of Linear Electrooptic Effect in Poled Amorphous Silica-Based Materials</i>	PhD	Physics	1998
Xiaolan Chen	<i>A Study of Interferometric Lithography: Approaching the Linear Systems Limit of Optics</i>	PhD	ECE	1998
Thomas G. Alley	<i>The Formation of the Second-Order Nonlinearity in Poled Fused Silica</i>	PhD	Physics	1998
Jonathan Stohs	<i>Epitaxial Structure Dependence of Gain, Refractive Index,</i>	PhD	Physics	2000

	<i>and Linewidth Enhancement Factor in GaAs and InGaAs Broad-Area Quantum Well Lasers</i>			
Yanmin Wu	<i>Labview Programming for Lithographic Applications</i>	MS	ECE	2001
Michael J. O'Brien II	<i>Advances in Optics-Based Chemical and Biosensors with Array Applications</i>	PhD	Opt. Sci. Physics	2002
Tengiz Svimonishvili	<i>Dual Closed-Loop Optoelectronic Auto-Oscillatory Detection Circuit for Monitoring Fluorescence-Lifetime-Based Chemical/Biological Sensors and Sensor Arrays</i>	MS	ECE	2002
Seung Chang Lee	<i>Nanoscale Exitaxial Growth by Molecular Beam Epitaxy and Its Applications</i>	PhD	ECE	2002
Alex Raub	<i>Deep-UV Immersion Interferometric Lithography</i>	MS	ECE	2002
Babar Minhas	<i>Modeling of Two-Dimensional Resonant Structures</i>	PhD	ECE	2002
Christian Schwarz	<i>Imaging Interferometric Lithography and Microscopy</i>	PhD	Physics	2003
Ashwani Sharma	<i>Effects of Dimensional Nanoscaling on the Optical and Electronic Properties of Silicon Films-Walls-Wires</i>	PhD	ECE	2004
David Burckel	<i>Generalized Transverse Bragg Waveguides</i>	PhD	ECE	2004
Wenjun Fan	<i>Linear and Nonlinear Infrared Optical Properties of Subwavelength Coaxial Metallic Arrays</i>	PhD	ECE	2005
Shuang Zhang	<i>Infrared Magnetic and Negative Index Metamaterials</i>	PhD	ECE	2005
Jing Luo	<i>Second-Order Nonlinearity of Thermally-Poled Lead-Silicate Glass Waveguides</i>	PhD	ECE	2006
Yuliya Kuznetsova	<i>Imaging Interferometric Microscopy – Resolution to the Limit of Frequency Space</i>	PhD	Physics	2007
Liang Xue	<i>Widely Tunable Infrared Lasers</i>	PhD	ECE	2008
Jingyu Zhang	<i>Metallic Photonic Crystals: Transmission Resonances and Second Harmonic Generation</i>	PhD	ECE	2009
Svyatoslav Smolev	<i>Progress in Metamaterials: Magnetic Hybridization of Electric Dipole Resonance and Inhomogeneous Structures for Thin-Film Lenses</i>	PhD	ECE	2010
Zahyun Ku	<i>All-Optical Metamaterial Modulators – Fabrication, Simulation and Characterization</i>	PhD	ECE	2010
Alex Raub	<i>Large-Area 3D Photonic Crystals with Embedded Waveguides</i>	PhD	ECE	2010

Current Graduate Students

Xiang He	ECE	PhD	ECE
Alexander Neumann	Physics	PhD	Physics
Anibil Chowdhuri	Physics	PhD	Physics
Ruichao Zhu	ECE	PhD	ECE
Chingyi Li	ECE	PhD	ECE

Grants and Contracts:

Principal investigator on numerous grants and contracts with federal agencies while at MIT Lincoln Laboratory.

Since joining the University of New Mexico in August, 1985 grants and contracts have included:

Project Title	Sponsor	Award Total	Period
Equipment grant to purchase a cw mode-locked YAG/dye laser system	NSF	\$65,700	1986
High Power Semiconductor Diode Lasers	Spectra Diode Lab	\$99,792	1986-1987
Optoelectronics Research Center	AFOSR	\$22,499,256	1986-2011
Program to Develop High Performance 10-GHz Ultra-violet Photomixers	MIT Lincoln Lab	\$461,722	1986
High-Speed UV Detector Development	MIT Lincoln Lab	\$31,575	1987
Laser Semiconductor Interactions	AFOSR	\$1,085,540	1986-1991
Optoelectric Device and Materials Research	NSF	\$50,000	1987
Description and Specifications for Program to Develop High-Performance 10 GHz Ultraviolet Photomixers	NRL	\$51,398	1988
Micro-Raman Measurements of Diode Lasers	IBM	\$48,953	1988
SEMATECH Center of Excellence for On-Line Analysis and Metrology	SEMATECH/SRC	\$2,314,937	1988-1992
Journal of Quantum Electronics	IEEE/LEOS	\$147,055	1989-1994
JQE Editors Office	JQE	\$26,468	1989
Undergraduate Faculty Enhancement in Semiconductor Optoelectronics	NSF	\$161,966	1988-1989
Optoelectronics Materials Center	DARPA	\$12,323,656	1990-1996
Alliance for Phonic Technology	SNL	\$19,900	1991
Metrology and On-line analysis for semiconductor manufacturing	SRC/SEMATECH	\$2,036,405	1991-1994
SRC Travel Grant	SRC/SEMATECH	\$8,321	1991-1992
APT Funding for FY 92	LANL	\$221,302	1992-1994
Large Second Order Nonlinearity in Fused Silica	Draper Laboratories	\$121,308	1992-1994
Diagnostic for In-Situ Temperature Measurement During Epitaxial Growth	Hughes Research Laboratories	\$110,000	1993-1995
Integrated Fused Silica Modulators	Draper Laboratories	\$124,536	1993-1995
Stage for Soft X-Ray Projection Lithography	SNL	\$150,000	1993-1994
Development for the Generation of Microstructures using Multiple-exposure Interferometric Lithography	SRC/SEMATECH	\$10,000	1994
IPA - various	AFOSR	\$1,867,970	1994-2009
Measurement of the Linewidth Enhancement Factor at High Excitation Levels	AFOSR	\$118,306	1994
SRC Senior Student Support Grant	SRC/SEMATECH	\$67,500	1994

Interferometric Lithography Development	SNL	\$159,744	1996-1997
Interferometric Lithography for Nanoscale Fabrication	DARPA	\$1,065,256	1996-2000
A Feasibility Study of UV Polarizers	Moxtek	\$15,000	1997
Equipment Support for Interferometric Mix & Match Lithography	SEMATECH	\$488,949	1997
Interferometric Lithography for 0.18 μm Features	Novellus	\$5,000	1997
Linewidth Enhancement Factor for Semiconductor Diode Lasers	AFOSR	\$135,135	1997-2000
Manufacturable IR Photonic Crystals Based on Interferometric Lithography	ARO	\$515,246	1997-1999
Method of Fabricating A Dynamic Random Access Memory with Textured, Area Enhancing Structures Using	Texas Instruments	\$48,750	1997
Random and Uniform Reactive Ion Etching Texturing of Si	SNL	\$74,998	1997
SRI Task Order Contract	SRI International	\$156,450	1997-1998
APT Support from AFRL	NMIMT	\$32,400	1998-2000
Development of 1.06 μm Fiber-Based Switch	Hughes Danbury Optical Systems	\$64,473	1998
Manufacturable, Multi-Dimensional High Capacity Optoelectronic Interconnects	DARPA	\$4,974,407	1998-2003
Deep Subwavelength Optical Nanolithography (MURI)	ARO	\$5,391,598	1999-2004
Hydrogen Transport in Oxides	SNL	\$94,419	1999-2000
Investigation of Large-Period Gratings by Interferometric Lithography	Cymer	\$57,190	1999-2000
Modeling for Imaging Interferometric Lithography	SEMATECH	\$61,308	1999
Nanowire Gate-All-Around Mosfet: Design, Fabrication and Characterization	University Space Research Association	\$20,000	1999
Ultra-Thin Solar-Blind Silicon Photodectors	ONR	\$197,645	1999
Demonstration of Interferometric Lithography for Field Emission Devices	SRI International	\$8,997	2000
High Capacity Optoelectronics Interconnects	DARPA	\$6,946,311	2000-2006
Professional Services of Shoaib Zaidi	Wavefront Science	\$35,776	2000
Radiation Sensitivity of Unique Memory Devices	AFRL	\$43,771	2000-2001
High Dielectric Constant Oxides for Advanced Micro-electronics Application	AFRL	\$815,165	2001-2003
Space Electronics Modeling, Development and Experimentation (SEMDE) UNM-3	Mission Research	\$299,421	2001-2003
Development of Interferometric Lithography Techniques for Distributed Feedback Mid-infrared Interband Semi Lasers	Maxion, Inc.	\$40,000	2002-2004
Growth of Direct Patterned Quantum Dots	SNL	\$513,487	2002-2013
Optical Advisory Services	SRI International	\$516	2002-2003

Research in Liquid Immersion Lithography	SEMATECH	\$105,000	2003-2004
Developing and Modeling Fiber Lasers and Fiber Amplifier	AFRL	\$35,960	2004
Interferometric Lithography of Photonic Crystals	SNL	\$65,000.00	2004-2005
National Nanotechnology Information Network (NNIN)	Cornell University	\$2,831,5000	2004-2008
OMC: Spatial, Temporal and Spectral Localization for Advanced Photonics Capabilities	DARPA	\$5,139,327	2004-2008
Pupil filtering and Super-Resolution Imaging in Super High NA Immersion Lithography	Intel	\$140,000	2004
Si nanowire devices for high-performance RF and digital applications	AFOSR	\$45,000	2004
Developing Pulsed Fiber Lasers	AFRL	\$117,274	2005-2007
Development of Nanofluidic Chips	Redondo Optics	\$150,000	2006
High Operating Temperature Mid-Wave Infrared Focal Plane Arrays (HOT MWIR)	Lockheed Martin Corporation	\$1,238,500	2006-2008
Interferometrically Defined GaN Nanoneedles for Defect Reduction in GaN-based LED's	DARPA	\$250,000	2006-2007
High Power Laser Development	AFRL	\$577,652	2007
REU: Nanotechnology REU Program for NNIN 2007-2009	Cornell University	\$28,800	2007-2008
Metamaterials Grand Challenge	SNL	\$70,000	2008
Nanofabrication for THZ Spectroscopy: Nanochannels and Nanodots	ARO	\$250,000	2008-2011
Support for the 52nd EIPBN	AFOSR	\$5,000.00	2008
Chipscale Nanofluidics for Chemical and Biological Separation and Sensing	NSF	\$606,400	2005-2011
EFRC for Solid-State-Lighting Science: Exploring Energy Conversion in Tailored Photonic Structures	SNL	\$375,000	2009-2014
Integration of Block-Copolymer with Nanoimprint Lithography: Pushing the Boundaries of Emerging Nanopatterning Technology	SNL (NINE)	\$255,000	2009-2012
STTR Phase I: High Efficiency Thin-film Photovoltaics on Low-cost Substrates by Layer Transfer	Gratings Inc.	\$75,000	2009-2010
Tunable Infrared Semiconductor Lasers	AFOSR	\$696,176	2008-2010
Tunable IR Lasers for Gas-Phase Sensing	NSF	\$690,176	2005-2011
Chirped Grating Tunable Lasers for the Infrared Molecular Fingerprint Spectral Region	DTRA	\$679,150	2010-2011
Nanoscale semiconductor electronics	AFRL	\$400,000	2010-2013
Radiation Effects in III-V Nanowire Devices	DTRA	\$1,050,000	2011-2014
SBIR Phase I in Tunable Infrared Lasers	Southwest Sciences	\$23,000	2011
Nanofluidics for DNA Separations	Redondo Optics DOD subaward	\$50,000	2011-2012
Unstable Resonator Mid-Infrared Laser Sources	AFOSR	\$530,468	2012-2015

Nanosystems Engineering Research Center (NERC) for Nanomanufacturing Systems for Mobile Computer Enabled Technologies (NASCENT)	UTA (NSF ERC subaward)	\$2,884,457	2012-2017
TOTAL UNM FUNDING AS PI		\$111,332,318	

Professional Society Affiliations:

American Association for the Advancement of Science (fellow)
 American Physical Society
 Institute of Electrical and Electronics Engineers (life fellow)
 Materials Research Society
 Optical Society of America (fellow)

Professional Activities:

Conference Organizing and Program Committees:

Lithography Wkshop'13	Co-Chair
EIPBN'11-'13	Advisory and Program Committees
EIPBN'10	Senior Past Chair
EIPBN'09	Junior Past Chair
EIPBN'08	Conference Chair
EIPBN'07	Steering Committee
EIPBN'06	Steering Committee
PhAST'05	Senior Past Chair
PhAST'05	Photonics in Nanotechnology Symposium Chair
EIPBN'05	Steering Committee (General Chair 2008)
EIPBN'04	Program Committee, Optical Lithography Section
PhAST'04	Photonics in Nanotechnology Symposium Chair
PhAST'04	Founding General Co-Chair;meeting co-located with CLEO/IQEC
DoD Nanomaterials	Co-Chair, Electronic Materials
CLEO'03	Chair, Long Range Planning Committee
EIPBN'02	Program Committee, Optical Lithography Section
EIPBN'01	Program Committee, Optical Lithography Section
BPPG'01	Program Committee, Glass Poling Section
CLEO'00-02	Chair, Steering Committee
CLEO'00	General Co-Chair
BPPG'99	Program Committee, Nonlinear Optical Processes
ICOSN'99	Co-chair, Joint Opt. Soc. Japan/SPIE Meeting
CLEO'99	LEAP Co-Chair
CLEO'98	Program Committee Co-Chair
SPIE'Photonics East	Doped Fiber Devices II
CLEO Pacific Rim'97	Program Committee in Nonlinear Optics
APS March Mtg.'97	Physics of Fiber Optics
SPIE'96	Doped Fiber Devices
CLEO Pacific Rim'95	Program Committee in Nonlinear Optics
Electrochem Soc.	International Symposium on Advanced Luminescent Materials (1995)
OSA	Topical Mtg: Photosensitivity and Quadratic Nonlinearity in Glass Waveguides: Fundamentals and Applications (1995)
MRS	Rapid Thermal and Integrated Processing IV (1995)
MRS	Rapid Thermal and Integrated Processing III (1994)
LEOS	New Semiconductor Lasers and Applications (1990)
CLEO'90	Optical Materials and Fabrication (chair)
IEEE/OSA	Nonlinear Optics (1990)
SRC	Metrology for Semiconductor Manufacturing (chair)
CLEO'89	Nonlinear Optics and Spectroscopy
LEOS'88	Optoelectronics
CLEO'88	Nonlinear Optics and Spectroscopy
CLEO'87	Nonlinear Optics and Spectroscopy (chair)
Southwest Conference on Optics'87	Program Coordinator

OSA/LEOS	Laser Diagnostics of Materials 1987(program chair)
IQEC'86	Semiconductor Nonlinear Optics
MRS	Laser Diagnostics and Processing for Semiconductor Device Materials (1982)
CLEO'82	Nonlinear Optics and Spectroscopy
Intl Conf. on Lasers and Applications (Rio. Brazil)	coordinator, 1982

Editorial:

IEEE Journal of Special Topics in Quantum Electronics	
Founding Editor	1995
IEEE Journal of Quantum Electronics	
Editor	1989-1994
Associate Editor	1986-1988
<i>Optics Letters</i>	
Associate Editor	1984-1986

Other:

Center for Integrated Nanotechnologies (SNL/LANL)	
Member, Scientific Advisory Committee	2003-2011 2013-

IEEE/LEOS:

Member, Engineering Award Committee	1997
Chair, Streifer Scientific Award Committee	1995
Member, Quantum Electronics Award Committee	1993-1994
Member, Fellow Award Committee	1993
Elected member of Board of Governors	1989-1991
Publications Committee Chair	1988

OSA:

<i>Member, Quantum Electronics Award Committee</i>	2005
<i>Member, Award Committee</i>	2004
<i>Member, Adolph Lomb Award Committee</i>	2000-2002
<i>Member, Nick Holnyak Jr. Award Committee</i>	1998
<i>Chair, Nick Holnyak Jr. Award Committee</i>	1997

National Academies:

National Member (for exceptional service to the National Research Council)	2011
Air Force Studies Board	2011-
Committee on Seeing Photons:	
Progress and Limits of Visible and Infrared Sensor Arrays (chair)	2009-2010
Committee on Nanophotonics Availability and Accessibility	2008
Standing committee on Avoiding Technological Surprise	2005-2011
Committee on Avoiding Technological Surprise	2004-2005
Committee on the Implications of	
Micro and Nano Technology for the Air Force (chair)	2001-2002
Committee to Provide an Assessment of Science and Technology for the	
Army After Next with an Emphasis on Logistics (AAN-LOG)	1997-1999
Research Assistantship Committee	1989-1995
Member, Committee. on Recom. for U. S. Army Basic Sci. Res.	1980-1985

Office of the Secretary of Defense

Advanced Research in Environmental Sensing II (ARES-II) participant	2001
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Army Research Office:

Electronics Program Strategic Planning Meeting	2001
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Member, Electronics Program Board of Visitors	1999
University Review Panels:	
Ghulam Issaq Khan Institute, Topi, Pakistan, International Advisory Board	1999
University of North Carolina at Charlotte, Physics Department Review	1996
Materials Research Society:	
Finance Committee Member	1983-1985
American Physical Society:	
Executive Committee, New England Section	1982-1984

Awards:

Outstanding Researcher, College of Engineering, University of New Mexico, 1991
Life Fellow of the Institute of Electrical and Electronics Engineers
Fellow of the Optical Society of America
Fellow of the American Association for the Advancement of Science
IEEE Third Millennium Medal
Kreidl Memorial Lecturer, NM Materials Society, 2008
New Mexico Business Weekly, "Who's who in Technology," 2009
STC Innovation Fellow, 2010
National Member of the National Research Council

REFEREED JOURNAL PUBLICATIONS**S. R. J. BRUECK**

- G. Bekefi, A. Bers and S. R. J. Brueck
Microwave Emission from n-Type InSb at 4.2 and 77K
Phys. Rev. Lett. **119**, 24 (1967)
- G. Bekefi, A. Bers and S. R. J. Brueck
Microwave Instability in n-Type Indium Antimonide
IEEE Trans. Electron Devices, **ED-14**, 593 (1967)
- R. E. Slusher, W. Giritat and S. R. J. Brueck
Multiphoton-Injected Plasmas in InSb
Phys. Rev. **183**, 758 (1969)
- A. Mooradian, S. R. J. Brueck and F. A. Blum
Continuously Stimulated Spin-Flip Raman Scattering in InSb
Appl. Phys. Lett. **17**, 481 (1970)
- S. R. J. Brueck and A. Mooradian
Efficient, Single Mode, cw, Tunable Spin-Flip Raman Laser
Appl. Phys. Lett. **18**, 229 (1971)
- S. R. J. Brueck and A. Mooradian
Near Resonance Spin-Flip Raman Scattering in Indium Antimonide
Phys. Rev. Lett. **28**, 161 (1972)
- S. R. J. Brueck and F. A. Blum
Linewidth of Spontaneous Spin-Flip Light Scattering in InSb
Phys. Rev. Lett. **28**, 1458 (1972)
- A. Mooradian, S. R. J. Brueck, E. J. Johnson and J. A. Rossi
Electric Field Induced Transient Spin-Flip Raman Laser Pulses in InSb
Appl. Phys. Lett. **21**, 482 (1972)
- S. R. J. Brueck, A. Mooradian and F. A. Blum
Near Resonance Spontaneous Spin-Flip Light Scattering in InSb
Phys. Rev. **B7**, 5253 (1973)
- S. R. J. Brueck and A. Mooradian
Spontaneous Spin-Flip Raman Linewidth and Nonlinear Processes in InSb
Optics Commun. **8**, 263 (1973)
- M. A. Guerra, S. R. J. Brueck and A. Mooradian
Gradient Field Permanent Magnet Spin-Flip Laser
IEEE J. Quantum Electron. **QE-9**, 1157 (1973)
- Steven R. Brueck and Aram Mooradian
Frequency Stabilization and Fine-Tuning Characteristics of a cw InSb Spin-Flip Laser
IEEE J. Quantum Electron. **QE-10**, 634 (1974)

- S. R. J. Brueck and A. Mooradian
External Cavity CO₂-Pumped InSb Spin-Flip Laser
IEEE J. Quantum Electron. **QE-12**, 201, (1976)
- S. R. J. Brueck and R. M. Osgood, Jr.
Vibrational Energy Relaxation in Liquid N₂-CO Mixtures
Chem. Phys. Lett. **39**, 568 (1976)
- S. R. J. Brueck and A. Mooradian
Transient InSb Spin-Flip Laser - A Measurement of T₁
Opt. Commun. **18**, 539 (1976)
- H. Kildal and S. R. J. Brueck
Resonant Infrared Third-Harmonic Generation in Cryogenic Liquids
Phys. Rev. Lett. **38**, 347 (1977)
- S. R. J. Brueck
Vibrational Two-Photon Resonance Linewidths in Liquid Media
Chem. Phys. Lett. **50**, 516 (1977)
- S. R. J. Brueck, T. F. Deutsch and R. M. Osgood, Jr.
Vibrational Energy Relaxation of CH₃F Dissolved in Liquid O₂ and Ar
Chem. Phys. Lett. **51**, 339 (1977)
- S. R. J. Brueck
Polarized Vibrational Raman Scattering Lineshape Parameters in Liquid CO and Liquid CO-O₂ Mixtures
Chem. Phys. Lett. **53**, 273 (1978)
- Helge Kildal and S. R. J. Brueck
Infrared Four-Wave Sum and Difference Frequency Generation in Liquid CO-O₂ Mixtures
Appl. Phys. Lett. **32**, 173 (1978)
- T. F. Deutsch and S. R. J. Brueck
Collisionless Intramolecular Energy Transfer in Vibrationally Excited SF₆
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- 6,596,377 S. D. Hersee, S. R. J. Brueck, Saleem H. Zaidi and David Zubia, Thin Film Product and Method of Forming, (filed 3/27/00; issued 7/22/03).
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- 7,329,871 B2 W. Fan, S. Zhang, K. J. Malloy and S. R. J. Brueck, Plasmonic Enhanced Infrared Detector Element (UNM provisional filed 2/4/2005; issued 2/12/2008)
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- 8,337,390 Deying Xia and S. R. J. Brueck, Anisotropic Wetting Behavior on One-Dimensional Patterned Surfaces and Microfluidic Applications (issued 2/19/2013; utility patent application 12/475,371 filed 5/29/2009; UNM2009-003-02)
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UNM-760 *Large Area Patterning using Interferometric Lithography*, A. K. Raub, A. Frauenglass, and S. R. J. Brueck, (20070274633)

UNM-942 S. C. Lee and S. R. J. Brueck, *Cubic Phase, Nitrogen-Based Compound Semiconductor Films Epitaxially Grown on a Grooved Si(001) Substrate* (provisional 61/146,034 filed Jan. 21, 2009; utility application 12/691,463 filed 1/21/2010).

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UNM-1025 S. C. Lee, S. Krishna and S. R. J. Brueck, *Plasmonic Photodectors for Focal Plane Arrays* (utility application see UNM-992; provisional filed March 1, 2010)

UNM-2011-042 A. K. Raub and S. R. J. Brueck, *Large-Area Photonic Crystals with Embedded Waveguides* (provisional 23 Nov. 2010, utility 2/3/2012).

Provisional Patents Filed:

UNM-1055 S. C. Lee and S. R. J. Brueck, *Selective Nanoscale Patterned Growth of GaAs on Si(001) with sub-100-nm Silica Nanoparticles*, (provisional 61/403, filed 9/14/2010)

UNM-2012-007 S. C. Lee, S. D. Hersee and S. R. J. Brueck, *GaN growth on Si(001) for Electronic Applications* (provisional 14 July 2011).

UNM 2012-110 Steven R. J. Brueck, Seung-Chang Lee, Christian Wetzel, Teeradetch Detchprohm, and Christoph J. M. Stark, *Growth and Fabrication of Light Emitting Diodes using Cubic InxGa1-xN Quantum Wells Grown on Patterned Si (001) Substrates* (Provision Patent Application 61/642,680 filed May 4, 2012)

UNM-2012-012 S. R. J. Brueck, Steve Benoit and Xiang He, *Widely Tunable Optically Pumped Mid-IR Distributed Feedback Lasers* (provisional filed May 3, 2012).

INVITED PRESENTATIONS**S. R. J. BRUECK**

- Frequency Control of a Spin-Flip Laser*
American Physical Society March Meeting
San Diego, CA 1973
- Spin-Flip Raman Scattering*
International Conference on the Physics of Semiconductors
Stuttgart, Federal Republic of Germany 1974
- Vibrational Energy Relaxation in Liquid N₂-CO Mixtures*
International Conference on Lasers and Applications
Loen, Norway 1976
- Resonant Infrared Third Harmonic Generation in Cryogenic Liquids*
Seventh Winter Colloquium on High Power Visible Lasers
Park City, UT 1976
- Vibrational Energy Transfer Processes in Simple Cryogenic Liquids*
Gordon Research Conference on Molecular Energy Transfer
Wolfeboro, NH 1977
- Nonlinear Optics of Cryogenic Liquids*
Gordon Research Conference on Nonlinear Optics
Wolfeboro, NH 1977
- Resonant Infrared Four-Wave Mixing in Cryogenic Liquids*
Optical Society of America Annual Meeting
Toronto, Ontario, Canada 1977
- Molecular Vibrations in Simple Liquids - Spectroscopy, Kinetics and Applications*
Harvard/MIT Physical Chemistry Colloquium
Cambridge, MA 1978
- Vibrational Kinetics in Cryogenic Liquids and Applications to Nonlinear Optics*
Society of Photo-Optical Instrumentation Engineers Meeting
San Diego, CA 1978
- Nonlinear Optics of Cryogenic Liquids*
International Conference on Lasers and Applications
Rio de Janeiro, Brazil 1980
- Excitation of Surface Optical Waves and Material Ripples by Stimulated Scattering*
Optical Society of America Annual Meeting
Tucson, AZ 1982
- Optical Microanalysis of Small Device Structures*
Materials Research Society Meeting
Boston, MA 1982

- Optical Analysis of Semiconductor Materials, Structures and Processing*
CLEO
Anaheim, CA 1984
- Optical Microanalysis of Device Materials and Structures*
International Conference on Laser Processing and Diagnostics: Applications to Electronic Materials
Linz, Austria 1984
- Laser Diagnostics of Semiconductor Fabrication Processes and Devices*
Materials Research Society Meeting
Boston, MA 1984
- Laser Probes of Semiconductor Materials and Devices*
IBM Europe Institute
Oberlech, Austria 1985
- Microstructure Electromagnetic Effects*
OSA Annual Meeting
Washington, DC 1985
- Stimulated Surface Wave Scattering*
International Laser Symposium
Dallas, TX 1985
- Microstructure Electromagnetic Effects in Laser-Material Interactions*
16th Winter Colloquium on Quantum Electronics
Snowbird, UT 1986
- Optical Probes of Semiconductor Materials and Devices*
Laser Processing of Semiconductors
Microstructure Effects in Laser-Material Interactions
12th Nathia Gali International Summer College
Nathia Gali, Pakistan 1987
- cw Operation of Surface Emitting Lasers*
IEEE Workshop on Diode Lasers
Baltimore, MD 1989
- Metrology Definitions*
SRC Topical Research Conference
Metrology for Semiconductor Manufacturing
Santa Fe, NM 1990
- Nonlinear Optics of Thin Film PLZT*
Tenth Intl. Vavilov Conf. on Nonlinear Optics
Novosibirsk, USSR 1990
- Submicrometer Lithographic Alignment and Overlay Strategies*
SPIE
San Diego, CA 1990
- Nonlinear Optics of Thin Film PLZT*
IEEE/LEOS and OSA Topical Research Conference on Nonlinear Optics
Kauai, HI 1990

- Gain Switching and High Power Operation of Surface Emitting Lasers*
Engineering Foundation Conference on
High-speed / High Frequency Optoelectronics
Palm Coast, FL 1991
- Metrology Matters*
SPIE Southcentral'91 Symposium
Monitoring and Characterization in Microelectronics Manufacturing
Dallas, TX 1991
- Realtime Temperature Measurement*
AT&T Bell Laboratories
Working Group on RTP Temperature Measurement
Murray Hill, NJ 1991
- Building Market Driven Research Programs and Consortia (panelist)*
Technology Commercialization, Innovative Alliances for Economic Development
Albuquerque, NM 1991
- Introduction to Moiré Interferometry and its Application to
Semiconductor Manufacturing*
LEOS'91
San Jose, CA 1991
- Ferroelectric Films for Integrated Optics*
International Symposium on Integrated Ferroelectrics
Monterey, CA 1992
- Temperature Measurement for RTP*
SEMATECH SCOE Coordination Meeting
Austin, TX 1992
- Real-Time Process Monitors for Semiconductor Manufacturing*
NATO Advanced Study Institute on *In-Situ* Processing
The Physics and Technology of Surface Modification
Viana Do Castelo, Portugal 1992
- Large Second-Order Nonlinearity in Fused Silica*
Gordon Research Conference on Optical Properties of Glass
Tilton, NH 1992
- Future Prospects of Optoelectronics*
Panel Discussion at OSA'92
Albuquerque, NM 1992
- Temperature Measurement for RTP*
MRS Spring 1993 Mtg. Symp. G
San Francisco, CA 1993
- Temporal and Spectral Studies of Large $\chi^{(2)}$ in Fused Silica*
SPIE Meeting on
Quebec City, Quebec, Canada 1993

Si-Based Optoelectronics ?

International Conference and School on Applications of Nonlinear Optics
Prague, Czech Republic 1993

University/Industry Relationships

Panel Discussion at SPIE Mtg on Optical Tools for Manufacturing
Boston, MA 1993

Real-Time Monitors for Semiconductor Manufacturing

Science and Technology of Manufacturing, Topical Symposium at the
American Vacuum Society National Symposium
Orlando, FL 1993

Scalable Fabrication and Optical Characterization of Mesoscopic Si Structures

American Physical Society, March Meeting
Pittsburgh, PA 1994

Temperature Measurement Panel Discussion

Materials Research Society, Spring Meeting
Symposium G: Rapid Thermal and Integrated Processing III
San Francisco, CA 1994

Applications of Thin-Film Nonlinear Optical Materials

Materials Research Society, Spring Meeting
Symposium on Epitaxial Oxide Thin Films and Heterostructures
San Francisco, CA 1994

Scalable Si Nanofabrication Technology

CLEO'94
Anaheim, CA 1994

Diffraction Techniques for Lithographic Process Monitoring and Control

Ion, Electron and Photon Beams for Lithography
New Orleans, LA 1994

Recent Advances in the Second-Order Nonlinear Optical Properties of Amorphous Silica Materials

SPIE, Doped Fiber Devices and Systems
San Diego, CA 1994

Scalable Fabrication and Optical Characterization of nm Si Structures

MRS Symposium: *Microcrystalline and Nanocrystalline Semiconductors*, Paper F4.1
Boston, MA 1994

Perspectives on Glass Poling (plenary presentation)

Topical Conference on Photosensitivity and Quadratic Nonlinearities in Glass Waveguides
Portland, OR 1995

Optoelectronic Diagnostics for Semiconductor Manufacturing

Manufacturing Subcommittee, Committee on Optical Science and Engineering,
National Research Council
Irvine, CA 1995

- Optical Diagnostics of Semiconductor Manufacturing Processes*
Materials Research Society Fall Meeting
Symposium L: Diagnostic Techniques for Semiconductor Materials Processing
Boston, MA 1995
- Interferometric Lithography for Field-Emitter Displays*
USDC "Open House" for Tool Manufacturers
San Jose, CA 1996
- Nonlinearities, SHG and Poling in Silica Fibers*
Optical Fiber Conference
San Jose, CA 1996
- Perspectives on Glass Poling*
First Sino-American Workshop on Microstructured Crystals for Nonlinear Optics
Nanjing, People's Republic of China 1996
- Poling of Optical Fiber Materials*
Fiber Materials for Electronics, Optoelectronics and Sensors
Materials Research Society
San Francisco, CA 1996
- Interferometric Lithography - A Novel Approach to Nanometer Structures*
Symposium on Computational Methods for Simulating IC Manufacturing Processes
Society for Industrial and Applied Mathematics (SIAM) Annual Meeting
Kansas City, MO 1996
- Interferometric Lithography - A Novel Approach to Nanometer Structures*
IEEE Lithography Workshop
Maui, HI 1996
- Interferometric Lithography for Field-Emitter Devices*
AVS Annual Meeting
Philadelphia, PA 1996
- Industry-University Interactions in Optoelectronics*
OIDA Executive Forum
Washington, DC 1996
- Standard Defect Wafers*
SEMATECH Analytical Managers Meeting
Austin, TX 1996
- Perspectives on Nanoscale Lithography*
Sixth NASA Symposium on VLSI Design
Albuquerque, NM 1997
- Interferometric Nano-Lithography for Periodic Pinning*
Flux, Quantum, and Mesoscopic Effects in Superconducting Materials and Devices
Santa Fe, NM 1997
- Interferometric Lithography - A Novel Approach to the nm Regime*
2nd International Conference on Future Information Technologies
Kita-Hiroshima, Hokkaido, Japan 1997

- Interferometric Lithography for Nanoscale Structures*
Gaseous Electronics Conference
Madison, WI 1997
- Material and Device Aspects of Poled Fused Silica*
American Ceramic Society/Optical Society of America
Bragg Gratings, Photosensitivity, and Poling in Glass Fibers and Waveguides
Williamsburg, VA 1997
- Imaging Interferometric Lithography – A Wavelength Division Multiplex Approach to Extending Optics*
EIPBN'98
Chicago, IL 1998
- Imaging Interferometric Lithography – A Wavelength Division Multiplex Approach to Extending Optics*
Gordon Conference on Nanostructure Fabrication
Tilton, NH 1998
- Imaging Interferometric Lithography - Optics to the "Max" and Beyond*
OpTec Research Conference
Bozeman, MT 1998
- Second-Order Nonlinearities in Poled Fibers*
European Conference on Optical Communications
Madrid, Spain 1998
- Spatial Frequency Analysis of Resolution Enhancement Techniques*
Optical Enhancements Workshop, International SEMATECH
Austin, TX 1998
- Interferometric Lithography for Nanoscale Fabrication*
Laser Applications in Microelectronic and Optoelectronic Manufacturing IV
SPIE Photonics West
San Jose, CA 1999
- The Year 2001 Lithography Problem*
Optoelectronics'99 (Plenary Presentation)
SPIE Photonics West
San Jose, CA 1999
- 25-nm Lithography in 2020* (panel discussion)
SPIE Microlithography'99 Emerging Technologies
Santa Clara, CA 1999
- Imaging Interferometric Lithography for Sub-Wavelength Resolution*
APS Centennial Meeting
Atlanta, GA 1999
- Poling of Fused Silica - A Never-Ending Process*
Novel Optical Materials and Applications (NOMA'99)
Cetraro, Italy 1999

<i>Imaging Interferometric Lithography – Extending Optics to Fundamental Limits and Beyond</i> Intl. Congress on Optics (ICO'99) San Francisco, CA	1999
<i>Space Charge in Thermally Poled Fused Silica</i> Bragg Gratings, Photosensitivity and Poling in Glass Waveguides (BGPP'99) Stuart, FL	1999
<i>Enhanced Detectors by Nanoscale Texturing</i> Photonics West San Jose, CA	2000
<i>A University View on Industry Roadmaps: Long-Term Perspectives on Short-Term Roadmaps</i> AAAS Annual Meeting Washington, DC	2000
<i>Imaging Interferometric Lithography: approaching fundamental optics limits</i> SPIE OptoSW Albuquerque, NM	2000
<i>Nanoheteroepitaxy – A Nanofabrication Route to Improved Epitaxial Growth</i> EIPBN'2000 Palm Desert, CA	2000
<i>Developments in Imaging Interferometric Lithography</i> IEEE Lithography Workshop St. John, USVI	2000
<i>Fabrication and Application of Semiconductor Nanostructures</i> Government Microelectronic Applications Conference GOMAC'01 San Antonio, TX	2001
<i>Nanostructure Enhanced Optical Interactions</i> American Physical Society March Meeting Seattle, WA	2001
<i>Lithography – Advances in Optics (tutorial)</i> OSA Annual Meeting Long Beach, CA	2001
<i>Nanostructures for Environmental Sensing</i> Biological Threat Reduction Conference Albuquerque, NM	2002
<i>Interferometric Lithography and Nanoscale Patterned Semiconductor Growth</i> Material Research Society Boston, MA	2002
<i>Implications of Emerging Micro- and NanoTechnologies</i> IROS'03 Las Vegas, NV	2003

<i>There are no Limits to Optical Lithography</i> SPIE Photonics West San Jose, CA	2004
<i>Nanoscale Epitaxial Growth – A New Paradigm</i> SPIE Photonics West San Jose, CA	2004
<i>NanoScale Epitaxial Growth – A New Paradigm</i> DOD Nanomaterials Conference Wailia, HI	2004
<i>Phat Photons and Nifty Nanoscience</i> CREOL Industrial Affiliates Orlando, FL	2004
<i>Photonics in Nanoscience</i> (plenary presentation) PhAST San Francisco, CA	2004
<i>There are NO Fundamental Limits to Optical Lithography</i> LEOS Annual Meeting Puerto Rico	2004
<i>Infrared Metamaterials and Plasmonics</i> Photonics West San Jose, CA	2005
<i>Phat Photons and Nifty Nanoscience</i> (plenary presentation) Laser Precision Microfabrication Williamsburg, VA	2005
<i>Implications of Emerging Micro- and Nanotechnologies</i> Nano Applications Summit 2005 Cleveland, OH	2005
<i>There are NO Limits to Optical Lithography</i> AMSE National Congress Orlando, FL	2005
<i>Nanophotonics for Infrared Detectors</i> 2 nd Symposium on Infrared Materials and Technologies State College, PA	2005
<i>Phat Photons for Nifty Nanoscience</i> nanoMems Kharagpur, India	2005
<i>Lithographic Tools for Nanophotonics</i> Nanophotonics Workshop Tysons Corner, VA	2006
<i>Large-Area Metamaterials by Interferometric Lithography</i> APS March Meeting Baltimore, MD	2006

- Interferometric Lithography and Directed Self-Assembly – Competitors and Complements to NanoImprint Lithography*
NanoImprint Workshop
Charlotte, NC 2006
- Plasmonics and Metamaterials: Linear and Nonlinear Optical Properties*
International Union of Radio Science (URSI)
Albuquerque, NM 2006
- Large-Area Interferometric Lithography Fabrication of Nanophotonic Materials*
IEEE Nano Conference
Cincinnati, OH 2006
- Nanophotonics and Plasmonics*
Advanced Electromagnetic Materials (Short course)
Mitre
Tysons Corner, VA 2006
- Large-Area Metamaterials and Plasmonics using Interferometric Lithography*
Metamaterials Summer School
Bad Honnef, Germany 2006
- Optical and Interferometric Lithography – Nanotechnology Enablers*
Future Technologies II
Washington, DC 2006
- Nanostructures by the Square Yard*
DARPA/DSRC Workshop
Advancing State-of-the-Art Nanofabrication of Complex Structures
Arlington, VA 2007
- Plasmonics and Negative Index Materials*
ICAM Workshop on Energy Transfer
Santa Fe, NM 2007
- Nanofabrication for Nanophotonics*
DARPA Workshop on Metamaterials
Arlington, VA 2007
- Large-Area Metamaterials by Interferometric Lithography*
Joint Conference on Information Science
Salt Lake City, Utah 2007
- Metamaterial Nanofabrication*
International Workshop on Electromagnetic Metamaterials
Los Alamos, NM 2007
- A Frequency Space Perspective on Double Patterning*
SPIE Photomask Conference
Monterey, CA 2007

- S. R. J. Brueck
Large-Area Nanolithography for Materials Research
N. J. Kreidl Memorial Lecture
Rio Grande Materials Research Society
Albuquerque, NM 2007
- S. R. J. Brueck
Nanostructures by the Square Yard: Large-Area Plasmonics and Metamaterials
IEEE LEOS – Boston Section Plasmonics Course
Lexington, MA 2007
- Large-Area Nanophotonics using Interferometric Lithography*
Photonics West
San Jose, CA 2008
- Introduction to Imaging*
Metamaterials Short Course
Estes Park, CO 2008
- Large-Area Fabrication of Metamaterials*
Metamaterials Short Course
Estes Park, CO 2008
- Large-Area Linear and Nonlinear Nanophotonics*
LEOS Annual Meeting
Newport Beach, CA 2008
- Large-Area Nanophotonics*
Workshop on WaveFunction Engineering and Control in Nanostructured materials
Los Alamos, NM 2009
- Linear and Nonlinear Properties of Large-Area Nanophotonics*
IQEC
Baltimore, MD 2009
- Linear and Nonlinear Properties of Large-Area Nanophotonics*
NSRC Contractors Meeting
Annapolis, MD 2009
- Epitaxial Growth on Nanoscale Patterned Surfaces*
ICMAT
Singapore 2009
- Imaging Interferometric Microscopy – Resolution to the Linear Systems Limit (plenary)*
EOS'09
Capri, Italy 2009
- Imaging Interferometric Microscopy – Resolution to the Linear Systems Limit*
LEOS'09
Antalya, Turkey 2009
- Large-Area Linear and Nonlinear Nanophotonics*
Workshop on Future Electronics
Rincon, PR 2009

<i>Large area Linear and Nonlinear Nanophotonics</i> Physics of Quantum Electronics Snowbird, UT	2010
<i>Large-Area Linear and Nonlinear Nanophotonics</i> EIPBN'10 Anchorage, AK	2010
<i>Seeing Photons: Progress and Limits of Visible and Infrared Focal Plane Arrays</i> IEEE Photonics Society Annual Meeting 2010 Denver, CO	2010
<i>Large-Area Linear and Nonlinear Nanophotonics</i> PQE'10 Snowbird, UT	2010
<i>Large-Area Linear and Nonlinear Nanophotonics</i> EIPBN'10 Anchorage, AK	2010
<i>Recent Progress in Metamaterials Research</i> Progress in Electromagnetics Research Symp. (PIERS) Marrakesh, Morocco	2011
<i>Imaging Interferometric Microscopy</i> Progress in Electromagnetics Research Symp. (PIERS) Marrakesh, Morocco	2011
<i>Functional Materials with Interferometric Lithography</i> Summer School on Nanomaterials and Fabrication University of Toronto Toronto, Ontario, Canada	2011
<i>Interferometric Imaging Nanoscopy</i> Summer School on Nanomaterials and Fabrication University of Toronto Toronto, Ontario, Canada	2011
<i>DNA Transport in Nanoparticle Porous-Wall Nanotubes</i> Nanoelectronics for Defense and Security (Nano-DDS) Brooklyn, NY	2011
<i>Surface Plasma Wave Enhanced Infrared Detection</i> International Conference on Metamaterials, 2011 Barcelona, Spain	2011
<i>Ultrafast Metamaterial Switching and Surface Plasma Wave Enhanced Infrared Detection</i> Workshop on Metamaterial Applications Virginia Beach, VA	2011
<i>III-V Nanowire Devices for Radiation Effect Studies</i> S. C. Lee, A. Chaudhuri, N. Youngblood, A. Sharma, D. Telesca and C. Mayberry GOMATech'12 Las Vegas, NV	2012

Surface-Plasma-Wave Enhanced Infrared Detectors
Photonics West
San Francisco, CA

2013

SEMINARS**S. R. J. Brueck**

- Spin-Flip Raman Scattering*
Frances Bitter National Magnet Laboratory
MIT
Cambridge, MA 1971
- Spontaneous and Stimulated Spin-Flip Raman Scattering in InSb*
Lawrence Livermore Laboratory
Livermore, CA 1973
- Spontaneous and Stimulated Spin-Flip Raman Scattering in InSb*
IBM San Jose Research Laboratory
San Jose, CA 1973
- Spontaneous and Stimulated Spin-Flip Raman Scattering in InSb*
Optical Sciences Center
University of Arizona
Tucson, AZ 1973
- Spontaneous and Stimulated Spin-Flip Raman Scattering in InSb*
University of California - Berkeley
Berkeley, CA 1973
- Spontaneous and Stimulated Spin-Flip Raman Scattering in InSb*
Aerospace Corporation
Los Angeles, CA 1973
- Spontaneous Spin-Flip Raman Scattering - Experimental*
Spin-Flip Raman Scattering - Theory
Stimulated Spin-Flip Raman Scattering in InSb
Heriot-Watt University
Edinburgh, Scotland, UK 1974
- Spin-Flip Raman Scattering*
National Research Council
Ottawa, Ontario, Canada 1975
- Vibrational Kinetics in Cryogenic Liquids and Applications to Nonlinear Optics*
Los Alamos Scientific Laboratory
Los Alamos, NM 1978
- Infrared Nonlinear Optics with Cryogenic Liquids*
Memorial University of Newfoundland
St. John's, Newfoundland, Canada 1979

- Nonlinear Susceptibilities of Liquids and Solids*
Research Laboratory of Electronics
MIT
Cambridge, MA 1980
- Nonlinear Optics of Simple Liquids*
Sandia Laboratories
Albuquerque, NM 1981
- Photoacoustic Spectroscopy of Liquids*
Air Force Weapons Laboratory
Albuquerque, NM 1981
- Nonlinear Susceptibilities in Condensed Matter*
Worcester Polytechnic Institute
Worcester, MA 1981
- Nonlinear Susceptibilities in Condensed Matter*
GTE Laboratories
Waltham, MA 1982
- Nonlinear Optics with Simple Molecular Liquids*
University of Toronto
Toronto, Ontario, Canada 1982
- Stimulated Surface Plasma Waves and the Formation of Surface Ripples in Laser-Material Interactions*
Bell Telephone Laboratories, Murray Hill, NJ 1982
- Laser Probing of Semiconductor Materials and Device Structures*
Boston Section IEEE
Quantum Electronics and Applications Society 1983
- Stimulated Surface Wave Scattering in Laser Material Interactions*
Raytheon Research Division Seminar
Lexington, MA 1983
- Stimulated Surface Wave Scattering in Laser Material Interactions*
MIT Quantum Optics Seminar
Cambridge, MA 1983
- Stimulated Surface Wave Scattering in Laser Material Interactions*
Technical University
Vienna, Austria 1983
- Microstructure Electromagnetic Effects in Laser-Material Interactions*
Columbia University Radiation Laboratory Seminar
New York, NY 1983
- Microstructure Electromagnetic Effects in Laser-Material Interactions*
Boston University Chemistry Department Seminar
Boston, MA 1983

- Microstructure Electromagnetic Effects in Laser-Material Interactions*
Hughes Research Laboratories
Malibu, CA 1984
- Laser-Microstructure Interactions*
University of Lund
Lund, Sweden 1984
- Microstructure Electromagnetic Effects in Laser-Material Interactions*
Norwegian Defense Research Establishment
Oslo, Norway 1984
- Optical Diagnostics of Semiconductor Materials, Structures and Processing*
Norwegian Defense Research Establishment
Oslo, Norway 1984
- Laser-Microstructure Interactions*
Norwegian Institute of Technology
Trondheim, Norway 1984
- Microstructure Electromagnetic Effects in Laser-Material Interactions*
Washington University Electrical Engineering Dept.
St. Louis, MO 1984
- Laser-Microstructure Interactions*
IBM T. J. Watson Research Center
Yorktown Heights, NY 1985
- Laser Probes of Semiconductor Materials and Processing*
Los Alamos National Laboratory
Chemistry Division Seminar
Los Alamos, NM 1985
- Microstructure Electromagnetic Effects*
Sandia National Laboratories
Albuquerque, NM 1985
- Electrooptics Research at the UNM Center for High-Technology Materials*
Photonics Alliance
Los Alamos, NM 1986
- Microstructure Electromagnetic Effects for Device Applications*
Sandia National Laboratory
Albuquerque, NM 1986
- Microstructure Electromagnetic Effects*
Physics Department Colloquium
North Texas State University
Denton, TX 1986
- Optical Probes of Semiconductor Materials and Devices*
OSA/IEEE-LEOS Joint Meeting
North Texas Chapter
Dallas, TX 1986

- Optical Diagnostics of Semiconductor Materials and Devices*
Texas Instruments Colloquium
Dallas, TX 1987
- Optoelectronics Research at UNM*
Colloquium - Optical Computing Center
University of Colorado
Boulder, CO 1988
- Surface-Emitting Lasers*
Albuquerque Section,
Optical Society of America
Albuquerque, NM 1988
- Optoelectronics Research at UNM:
Surface Emitters and MSM Photodiodes*
Bell Communications Research
Navesink, NJ 1988
- From Laser-Surface Diagnostics to Surface
Emitting Lasers*
IBM General Products Division
Tucson, AZ 1989
- On-Line Analysis and Metrology for Semiconductor Manufacturing*
National Institute for Standards and Technology
Gaithersburg, MD 1989
- Nonlinear Optics of PLZT Thin Films*
Sandia National Laboratories
Albuquerque, NM 1989
- Surface-Emitting Semiconductor Lasers*
MIT Lincoln Laboratory
Solid-State Division Colloquium
Lexington, MA 1989
- From Laser Surface Diagnostics to Surface Emitting Lasers*
United Technologies Research Center
Hartford, CT 1989
- Surface-Emitting Semiconductor Lasers*
Polaroid Corporation
Cambridge, MA 1989
- Nonlinear Optics of PLZT Thin Films*
Los Alamos National Laboratory
Los Alamos, NM 1989
- Surface-Emitting Semiconductor Lasers*
Materials Research Colloquium
AT&T Bell Laboratories
Murray Hill, NJ 1990

<i>Semiconductor Metrology</i> Microelectronics Development Laboratory Sandia National Laboratories Albuquerque, NM	1990
<i>High-Speed uv Detectors</i> Maxwell Laboratories San Diego, CA	1990
<i>Metrology Matters</i> Motorola Phoenix, AZ	1990
<i>Scatterometry Applications</i> KLA Instruments Santa Clara, CA	1990
<i>Metrology Matters</i> Texas Instruments Materials Science Colloquium Dallas, TX	1990
<i>Metrology Matters: A Review of the New Mexico SCOE</i> SEMATECH Austin, TX	1990
<i>Alignment and Overlay Measurement Strategies</i> SVG Lithography Norwalk, CT.	1991
<i>Uses of Gratings for Semiconductor Manufacturing Metrology</i> AT&T Bell Laboratories Murray Hill, NJ	1991
<i>Progress in Surface Emitting Lasers</i> Solid State Sciences Colloquium Stanford University Stanford, CA	1991
<i>Metrology Matters</i> IBM T. J. Watson Research Center Yorktown Hts., NY	1991
<i>Quantum Wires to Smart Pixels</i> Martin Marietta Research Laboratories Baltimore, MD	1991
<i>Quantum Wires to Smart Pixels</i> U. S. Army Laboratory Command Harry Diamond Laboratories Adelphi, MD	1991
<i>Quantum Wires to Smart Pixels</i> Motorola Phoenix Corporate Research Laboratory Phoenix, AZ	1991

<i>Metrology Matters</i> Motorola Semiconductor Products Sector Mesa, AZ	1991
<i>Metrology Matters</i> Advanced Micro Devices Sunneyvale, CA	1991
<i>Metrology Matters</i> Hewlett-Packard Palo Alto, CA	1991
<i>Quantum Wires to Smart Pixels</i> Hewlett Packard Central Research Laboratory Palo Alto, CA	1991
<i>Metrology Matters</i> Intel Research Laboratory Santa Clara, CA	1991
<i>Metrology Matters</i> Sandia National Laboratory Albuquerque, NM	1991
<i>Perspectives on Optical Lithography</i> Los Alamos National Laboratory Los Alamos, NM	1991
<i>Lithography Metrology</i> SEMATECH Austin, TX	1992
<i>Temperature Measurement for Rapid Thermal Processing</i> SEMATECH Austin, TX	1992
<i>Metrology Matters</i> Advanced Micro Devices Austin, TX	1992
<i>Quantum Wires to Smart Pixels</i> New Mexico State University Las Cruces, NM	1992
<i>Perambulations in Periodicity</i> University of New Mexico College of Engineering Research Excellence Award Albuquerque, NM	1992
<i>Quantum Wires to Smart Pixels</i> Rice University ECE Seminar Houston, TX	1992
<i>Darpa Optoelectronic Materials Center</i> Arlington, VA	1992

<i>Thin Films for Nonlinear Optics</i> Stanford University Stanford, CA	1992
<i>Metrology Matters</i> North Carolina State University Advanced Electronic Materials Processing Seminar Raleigh, NC	1992
<i>Si-Based Optoelectronics?</i> Ontario Laser and Lightwave Research Center University of Toronto Toronto, Ontario, Canada	1992
<i>Metrology for Sub-μm Lithography</i> AT&T Bell Laboratories Murray Hill, NJ	1992
<i>Si-Based Optoelectronics?</i> C. S. Draper Laboratories Cambridge, MA	1993
<i>Multiple Exposure Interferometric Lithography</i> Sandia National Laboratories, Livermore Livermore, CA	1994
<i>Nonlinear Optical Properties of Fused Silica</i> Deacon Research, Inc. Palo Alto, CA	1994
<i>Moiré Alignment and Overlay Measurements</i> KLA Instruments San Jose, CA	1994
<i>Optoelectronic Materials Center</i> Hewlett-Packard III-V Symposium Cupertino, CA	1994
<i>Multiple-Exposure Interferometric Lithography</i> Coloray Fremont, CA	1994
<i>Optoelectronics at UNM - from Networks to Measurement</i> National Institute of Standards and Technology Boulder, CO	1994
<i>Optical Properties of "Modified" Si</i> National Renewable Energy Laboratory Golden, CO	1994
<i>Si-Based Optoelectronics?</i> Texas Instruments Colloquium Dallas, TX	1994

- Multiple-Exposure Interferometric Lithography: Field-Emitter Tips to Quantum Structures.*
AT&T Bell Laboratories
Murray Hill, NJ 1994
- Si-Based Optoelectronics?*
Solid-State Physics Division Seminar
MIT Lincoln Laboratory
Lexington, MA 1994
- Interferometric Lithography for Flat Panel Displays*
Texas Instruments
Dallas, TX 1995
- Grating and Speckle Temperature Measurement for Si Manufacturing*
Semiconductor Process Development Center
Texas Instruments
Dallas, TX 1995
- Interferometric Lithography for Field-Emitter Applications*
Motorola Phoenix Corporate Research Laboratory
Phoenix, AZ 1995
- Interferometry -- From Metrology to a Novel 0.05- μ m Lithography*
SEMATECH
Austin, TX 1995
- Alignment, Overlay and Positioning*
SVGL
Wilton, CT 1995
- Perspectives on Glass Poling*
Quantum Electronics Seminar
Stanford University
Stanford, CA 1995
- Interferometric Lithography — A Novel Approach to nm-Scale Structures*
AMD
Sunnyvale, CA 1995
- Interferometric Lithography — A Novel Approach to nm-Scale Structures*
National Semiconductor Corporation
Santa Clara, CA 1995
- Interferometric Lithography — A Novel Approach to nm-Scale Structures*
Coherent, Inc.
Santa Clara, CA 1995
- Interferometric Lithography — A Novel Approach to nm-Scale Structures*
Ultratech Stepper Corporation
San Jose, CA 1995
- Interferometric Lithography for Nanoscale Fabrication*
Texas Instruments
Dallas, TX 1996

- Interferometric Lithography for Nanoscale Fabrication*
Sandia National Laboratories
Albuquerque, NM 1996
- Perspectives on Glass Poling*
Solid-State Optical Materials and Devices
National Taiwan University
Taipei, Republic of China 1996
- Current Directions in Nanoscale Lithography*
Solid-State Optical Materials and Devices
National Taiwan University
Taipei, Republic of China 1996
- Interferometric Lithography - A Novel Approach to Nanometer Structures*
Optical Specialities, Inc.
Fremont, CA 1996
- Interferometric Lithography - A Novel Approach to Nanometer Structures*
IBM Almaden Research Center
San Jose, CA 1996
- Interferometric Lithography for Nanoscale Fabrication*
Motorola Advanced Products Research & Development Center
Austin, TX 1996
- Interferometric Lithography for Nanoscale Fabrication*
Intel/UNM Distinguished Lecture Series
Rio Rancho, NM 1996
- Silica Poling and Interferometric Lithography - Two Sensor Technologies?*
Sandia National Laboratories
Albuquerque, NM 1996
- Imaging Interferometric Lithography for Arbitrary Patterns*
Texas Instruments
Dallas, TX 1997
- Imaging Interferometric Lithography for Arbitrary Patterns*
University of Texas, Microelectronics Research Center
Austin, TX 1997
- Imaging Interferometric Lithography for Arbitrary Patterns*
SEMATECH
Austin, TX 1997
- Imaging Interferometric Lithography for Arbitrary Patterns*
Motorola, APRDL
Austin, TX 1997
- Imaging Interferometric Lithography – Optics to the “Max” and Beyond*
Physical Sciences Seminar
IBM T. J. Watson Research Center
Yorktown Heights, NY 1998

- Imaging Interferometric Lithography – Optics to the “Max” and Beyond*
Silicon Valley Group Lithography
Wilton, CT 1998
- Imaging Interferometric Lithography -
A WDM Approach to Extending Optics beyond 100 nm*
SEMATECH
Austin, TX 1998
- Spatial Frequency Analysis of Resolution Enhancement Techniques*
MIT Nanostructures Laboratory
Cambridge, MA 1998
- Spatial Frequency Analysis of Resolution Enhancement Techniques*
MIT Lincoln Laboratory
Lexington, MA 1998
- Imaging Interferometric Lithography for Deep Sub-Wavelength CDs*
Intel Corporation
Santa Clara, CA 1999
- Imaging Interferometric Lithography for Nanoscale Fabrication*
Stanford University, Quantum Electronics Seminar
Stanford, CA 1999
- Imaging Interferometric Lithography for Deep Sub-Wavelength Structures*
IBM Almaden Research Center
San Jose, CA 1999
- Imaging Interferometric Lithography for Deep Sub-Wavelength Structures*
Center for Nanostructures
University of Wisconsin
Madison, WI 1999
- Deep Sub-Wavelength Optical Nanolithography*
Cymer, Inc.
San Diego, CA 1999
- Imaging Interferometric Lithography – Pushing Optics to Fundamental Limits*
Texas Tech Univ.
Lubbock, TX 1999
- Imaging Interferometric Lithography for Deep Sub-Wavelength Structures*
Microelectronics Research Center
University of Texas
Austin, TX 2000
- Imaging Interferometric Lithography*
ASML
Tempe, AZ 2000
- A Nanotechnology Perspective*
3M Research Laboratory
Austin, TX 2000

<i>Nanoscience Research at Center for High Technology Materials</i> Sandia National Laboratories Albuquerque, NM	2000
<i>Optoelectronics Research at CHTM</i> Intel Corporation Rio Rancho, NM	2001
<i>There are No Fundamental Limits to Optical Lithography</i> Army Research Laboratory Adelphi, MD	2002
<i>There are No Fundamental Limits to Optical Lithography</i> Naval Research Laboratory Washington, DC	2002
<i>There are No Fundamental Limits to Optical Lithography</i> MIT Lincoln Laboratory Lexington, MA	2002
<i>There are No Fundamental Limits to Optical Lithography</i> University of Toronto Toronto, Ontario, Canada	2002
<i>There are No Fundamental Limits to Optical Lithography</i> Oak Ridge National Laboratory Oak Ridge, TN	2002
<i>There are No Fundamental Limits to Optical Lithography</i> Vanderbilt University Nashville, TN	2002
<i>Nanostructures for Environmental Monitoring</i> Nanotechnology Workshop, UNM	2003
<i>Nanostructures for Biology?</i> UNM Biology Department Seminar	2003
<i>Phat Photons to Nifty Nanoscience</i> UNM Physics and Astronomy Department Colloquium	2003
<i>Phat Photons to Nifty Nanoscience</i> Arizona State University Seminar	2003
<i>There are NO Fundamental Limits to Optical Lithography</i> Sandia National Laboratories	2003
<i>Phat Photons and Nifty Nanoscience</i> Sandia National Laboratories	2004
<i>Phat Photons and Nifty Nanoscience</i> Los Alamos National Laboratory	2004
<i>Phat Photons and Nifty Nanoscience</i> Army Research Laboratory	2004

<i>Phat Photons and Nifty Nanoscience</i> University of Arizona, Optical Sciences Center	2004
<i>Phat Photons and Nifty Nanoscience</i> University of North Carolina, Charlotte	2004
<i>There are NO Fundamental Limits to Optical Lithography</i> Texas Instruments, Dallas	2004
<i>Photonic Crystals for Light Extraction from LEDs</i> Lumileds, Inc., San Jose, CA	2005
<i>Phat Photons and Nifty Nanoscience</i> SRI, Menlo Park, CA	2005
<i>Visible/Infrared Nanophotonics: Photonic Crystals, Plasmonics and Metamaterials</i> OSA Student Chapter, UNM	2005
<i>Phat Photons for Nifty Nanoscience</i> Sandia National Laboratories, Albuquerque, NM	2005
<i>Nanophotonics, Metamaterials, Negative Index and all that Jazz</i> Lockheed Martin Missiles and Fire Control, Orlando, FL	2005
<i>Nanophotonics and all that Jazz</i> SRI, Menlo Park, CA	2005
<i>Phat Photonics for Nifty Nanoscience</i> UCLA Electrical Engineering Colloquium Los Angeles, CA	2006
<i>Interferometric Lithography for Nanoscale Manufacturing</i> Intevac Santa Clara, CA	2006
<i>Beyond Rayleigh – Optics to the Min</i> KLA-Tencor Colloquium Milpitas, CA	2006
<i>Nanophotonics and Plasmonics</i> Presentation to National Academies Panel on Nanophotonics Albuquerque, NM	2006
<i>Phat Photons for Nifty Nanoscience</i> NIST Gaithersburg, MD	2007
<i>Phat Photons for Nifty Nano(Bio)Science</i> UNM IGERT Seminar Albuquerque, NM	2007
<i>Imaging Interferometric Microscopy – Approaching Nanoscopy</i> University of Arizona College of Optical Science Tucson, AZ	2008

<i>Imaging Interferometric Microscopy – Optics to the Nanoscale</i> Columbia University ECE Department Seminar New York, NY	2008
<i>Large-Area Nanopatterning – From Metamaterials to Nanofluidics</i> National University of Singapore Singapore	2009
<i>Functional Nanomaterials and Nanodevices by Interferometric Lithography</i> MIT Lincoln Laboratory Lexington, MA	2011
<i>Functional Nanomaterials by Interferometric Lithography</i> University of Texas at Austin Austin, TX	2012
<i>Imaging Interferometric Microscopy – Resolution to the Linear Systems Limits</i> NIST Gaithersburg, MD	2012

MEETING PRESENTATIONS (MOST RECENT FIVE YEARS)

S. R. J. Brueck

- S. R. J. Brueck (invited paper)
Lithographic Tools for Nanophotonics
 Nanophotonics Workshop, Tysons Corner, VA 2006
- S. R. J. Brueck (invited paper)
Large-Area Metamaterials by Interferometric Lithography
 APS March Meeting
 Baltimore, MD 2006
- N. Panoiu, R. M. Osgood, S. Zhang* and S. R. J. Brueck
Zero-n Band Gap in 1D Periodically Layered Photonic Superlattices
 APS March Meeting
 Baltimore, MD 2006
- W. Pan, R. G. Dunn, J. L. Reno, J. A. Simmons, D. Li* and S. R. J. Brueck
Anomalous Electronic Transport Features in a Lateral Quantum Dot Array Sample
 APS March Meeting
 Baltimore, MD 2006
- Y. Kuznetsova*, A. Neumann* and S. R. J. Brueck,
Imaging Interferometric Microscopy
 Fundamentals of Microscopy'06
 Perth, Australia 2006
- Deying Xia*, Dong Li*, Ying Luo*, Zahyun Ku*, Abani Biswas and S. R. J. Brueck
Lithographically Templated and Defined Surface Structures of Nanoparticle Films and Arrays---A Combination of "Bottom-Up" and "Top-Down" Methods
 AVS New Mexico Chapter Meeting
 Albuquerque, NM 2006
- O. Levi, W. Suh, M. M. Lee, J. Zhang*, S. R. J. Brueck, S. Han, and J. S. Harris
Guided Resonance in Photonic Crystal Slabs for Biosensing Applications
 CLEO'06
 Long Beach, CA 2006
- S. Zhang, W. Fan, K. J. Malloy, S. R. J. Brueck, N. C. Panoiu and R. M. Osgood
Optical Negative Index Metamaterials with Improved Performance
 CLEO'06
 Long Beach, CA 2006

- W. Fan, S. Zhang, A. Abdenour, S. Krishna, K. J. Malloy, S. R. J. Brueck, N. C. Panoiu and R. M. Osgood
Nano-Patterned Isotropic Nonlinear Material for Second Harmonic Generation without Phase Matching
CLEO'06
Long Beach, CA 2006
- Deying Xia*, D. Li*, Y. Luo*, and S. R. J. Brueck
Lithographically Defined Nanoparticle Patterns on Planar Surfaces,
EIPBN'06
Baltimore, MD 2006
- S. R. J. Brueck
Interferometric Lithography and Directed Self-Assembly – Competitors and Complements to NanoImprint Lithography (invited)
NanoImprint Workshop
Charlotte, NC 2006
- S. R. J. Brueck, S. Zhang, W. Fan, K. J. Malloy, N.-C. Panoiu and R. M. Osgood
Plasmonics and Metamaterials: Linear and Nonlinear Optical Properties (invited)
International Union of Radio Science (URSI)
Albuquerque, NM 2006
- S. R. J. Brueck
Large-Area Metamaterials and Plasmonics using Interferometric Lithography (Invited)
Metamaterials Summer School
Bad Honnef, Germany 2006
- Deying Xia and S. R. J. Brueck
Fabrication of Biomimetic Fluidic and Biosensor Structures by Directed Self-Assembly of Colloidal Silica Nanoparticles
MRS Spring Meeting
San Francisco, CA 2007
- Gabriel P. Lopez, S. R.J. Brueck, Sang M. Han, Cornelius F. Ivory, Dimiter N. Petsev and Scott S. Sibbett (invited)
Materials Processing Methods and Issues in the Development of Nanofluidic Systems for Biomolecular Analysis.
MRS Spring Meeting
San Francisco, CA 2007
- Mangesh T. Bore¹, Aurelio Evangelista*, Linnea Ista, Steven R.J. Brueck and Gabriel P. Lopez
Chip-Scale Affinity Microcolumn Biosensors for Toxic Agents
MRS Spring Meeting
San Francisco, CA 2007
- Y.-J. Oh*, Danny Bottenus*, D. N Petsev, S. R J Brueck, G. P. Lopez, C. F. Ivory and S. M Han
Study of FET Flow Control of Proteins and pH Changes in Nanochannels Using Scanning Laser Confocal Fluorescence Microscopy and Multiple Internal Reflection Fourier Transform Infrared Spectroscopy
MRS Spring Meeting
San Francisco, CA 2007

- A. Neumann*, Y. Kuznetsova* and S.R.J Brueck
Distortion correction in imaging interferometric microscopy at the $2/\lambda$ linear systems limit
Focus on Microscopy (FOM'07)
Valencia, Spain 2007
- L. Xue*, S. R. J. Brueck and R. Kaspi
CW, High-Power, Single-Longitudinal Mode Operation of an Optically Pumped Mid-IR DFB Laser
CLEO
Baltimore, MD 2007
- R. D. R. Bhat, N. C. Panoiu, R. M. Osgood, and S. R. J. Brueck
Enhancing Infrared Photodetection with a Circular Metal Grating
CLEO
Baltimore, MD 2007
- Z. Ku* and S. R. J. Brueck
Experimental Comparison of Circular, Elliptical and Rectangular (Fishnet) Negative-Index Metamaterials
QELS
Baltimore, MD 2007
- O. Levi, M. M. Lee, J. Zhang, V. Lousse, S. R. J. Brueck, S. Fan, J. S. Harris
Optical Characterization and Sensitivity Evaluation of Guided-Resonances in Photonic Crystal Slabs for Biosensing Applications
CLEO
Baltimore, MD 2007
- D. Li*, A. Frauenglass, A. Raub* and S. R. J. Brueck
Fabrication of 22-nm Half Pitch Lines by Single-Exposure, Self-Aligned, Spatial-Frequency Doubling
EIPBN'07
Denver, CO 2007
- D. Xia, Z. Ku*, D. Li*, and S. R. J. Brueck
Formation of Hierarchical Nanoparticle Patterns with Colloidal Lithography and Two-Step Self Assembly
EIPBN'07
Denver, CO 2007
- D. Xia and S. R. J. Brueck
Anisotropic Wetting Behavior of One-Dimensional Patterns and Application to Fluidic Devices
EIPBN'07
Denver, CO 2007
- S. R. J. Brueck
Large-Area Metamaterials by Interferometric Lithography
Joint Conference on Information Science
Salt Lake City, UT 2007
- S. R. J. Brueck
A Frequency Space Perspective on Double Patterning
SPIE Photomask
Monterey, CA 2007

- S. R. J. Brueck
Large-Area Nanolithography for Materials Research
N. J. Kreidl Memorial Lecture
Rio Grande Materials Research Society
Albuquerque, NM 2007
- S. R. J. Brueck (invited)
Large-Area Nanophotonics
Workshop on Frontiers of Electronics
Cozumel, MX 2007
- Deying Xia, T. Gamble, S. J. Koch, G. P. Lopez and S. R. J. Brueck (invited)
An Integrated Nanofluidic Chip with a 10^7 Linear-Dimension Dynamic Range
Workshop on Frontiers of Electronics
Cozumel, MX 2007
- S. R. J. Brueck (invited)
Large-Area Nanophotonics using Interferometric Lithography
Photonics West
San Jose, CA 2008
- A. Neumann,* Y. Kuznetsova and S. R. J. Brueck
Structured Illumination for Imaging Interferometric Microscopy
CLEO'08
San Jose, CA 2008
- Liang Xue,* S. R. J. Brueck and R. Kaspi
Large Tunability of an Optically Pumped Mid-IR Laser with Chirped Distributed Feedback Grating
CLEO'08
San Jose, CA 2008
- Jingyu Zheng,* and S. R. J. Brueck
Saturation of Second Harmonic Generation in Plasmon-Coupled GaAs-Filled Hole Arrays
QELS'08
San Jose, CA 2008
- Svyatoslav Smolev* and S. R. J. Brueck
Graded Index Optical Lens using Inhomogeneous Metamaterials
CLEO'08
San Jose, CA 2008
- Deying Xia, Thomas Gamble,* Gabriel Lopez and S. R. J. Brueck
Fabrication of Porous Nanochannels using Nanoparticles and Application to the Transport of DNA Molecules
EIPBN'08
Portland, OR 2008
- S. R. J. Brueck
Large-Area Linear and Nonlinear Nanophotonics (Invited)
LEOS Annual Meeting
Newport Beach, CA 2008

- S. R. J. Brueck
Large-Area Nanophotonics
 Workshop on WaveFunction Engineering and Control in Nanostructured materials
 Los Alamos, NM 2009
- Xiang He*, Deying Xia, Ying-Bing Jiang, Gabriel P. Lopez and S. R. J. Brueck
Tailoring Anisotropic Wetting Properties on One-Dimensional Nanopatterned Surfaces
 EIPBN
 Marco Island, FL 2009
- Alexander Neumann*, Yuliya Kuznetsova and S. R. J. Brueck
Imaging Interferometric Nanoscopy to the Limits of Available Frequency Space
 EIPBN
 Marco Island, FL 2009
- S. R. J. Brueck
Large-Area Linear and Nonlinear Nanophotonics (Invited)
 IQEC
 Baltimore, MD 2009
- R. Prasankumar, Zahyun Ku,* A. A. Gin, P. C. Upadya, S. R. J. Brueck, A. J. Taylor
Ultrafast Optical Wide-Field Microscopy
 CLEO
 Baltimore, MD 2009
- Liang Xue, S. R. J. Brueck and R. Kaspi
A Widely Tunable Chirped-Grating Distributed Feedback Laser for Spectroscopic Applications
 CLEO
 Baltimore, MD 2009
- Yuliya Kuznetsova, Alexander Neumann* and S. R. J. Brueck
Imaging Interferometric Nanoscopy to the Limits of Available Frequency Space
 CLEO
 Baltimore, MD 2009
- K. M. Dani, Zahyun Ku*, P. C. Upadhy, R. P. Prasankumar, S. R. J. Brueck and A. J. Taylor
Sub-Picosecond Optical Switching in the Near-Infrared using Negative Index Metamaterials
 IQEC
 Baltimore, MD 2009
- S. R. J. Brueck
Linear and Nonlinear Properties of Large-Area Nanophotonics (invited)
 DOE NSRC Contractors Review
 Annapolis, MD 2009
- S. R. J. Brueck and S. C. Lee
Epitaxial Growth on Nanoscale Patterned Surfaces (invited)
 ICMAT
 Singapore 2009
- D. Xia, S. R. J. Brueck, Y-M. Chiang and C. C. Wong
Formation of Surface Nanoparticle Patterns with Directed Self-Assembly and Nanolithography
 ICMAT
 Singapore 2009

- D. Xia and S. R. J. Brueck
Fabrication of Porous Nanochannels using Nanoparticles for Transport of DNA Molecules
 ICMAT
 Singapore 2009
- S. R. J. Brueck
Imaging Interferometric Microscopy – Resolution to the Linear Systems Limit (plenary)
 EOS'09
 Capri, Italy 2009
- S. R. J. Brueck
Imaging Interferometric Microscopy – Resolution to the Linear Systems Limit (invited)
 LEOS'09
 Antalya, Turkey 2009
- S. R. J. Brueck
Large-Area Linear and Nonlinear Nanophotonics
 WOFE'09
 Rincon, Puerto Rico 2009
- S. R. J. Brueck
Tunable IR Lasers by Chirped DFB Gratings
 WOFE'09
 Rincon, Puerto Rico 2009
- S. R. J. Brueck
Large Area Linear and Nonlinear Nanophotonics (invited)
 PQE'10
 Snowbird, UT 2010
- A. Neumann*, Y. Kuznetsova and S. R. J. Brueck
Imaging Interferometric Nanoscopy To The Limits Of Available Frequency Space
 Focus on Microscopy (FOM)
 Shanghai, China 2010
- Z. Ku*, K. M. Dani, P. C. Upadhyay, R. P. Prasankumar, A. J. Taylor and S. R. J. Brueck
Ultrafast, Dual-Band Optical Switching Device with a Negative-Index Metamaterial
 CLEO/QELS'10
 San Jose, CA 2010
- S. Smolev*, Z. Ku*, S. R. J. Brueck, I. Brener, M. Sinclair, G. Ten-Eyk, W. Langson and L. Basilio
Hybridization of the Negative Index Response by Resonant Coupling to a Dipole Absorber Inside a Metamaterial
 CLEO/QELS'10
 San Jose, CA 2010
- A. Raub* and S. R. J. Brueck
Large Area 3D Photonic Crystals with Embedded Waveguides
 EIPBN'10
 Anchorage, AK 2010

- S. Smolev, Z. Ku, S. R. J. Brueck, I. Brener, M. Sinclair, G. Ten Eyck, W. Langston* and L. Basilio*
Experimental Demonstration of Resonant Coupling to a Dipole Absorber Inside a Metamaterial: Hybridization of the Negative Index Response
 EIPBN'10
 Anchorage, AK 2010
- C-C. Liu, A. Raub*, P. Hakeem*, S. R. J. Brueck and P. Nealey
The Integration of Block Copolymer Directed Assembly with 193 Immersion Lithography
 EIPBN'10
 Anchorage, AK 2010
- S. R. J. Brueck (invited)
Large-Area Linear and Nonlinear Nanophotonics
 EIPBN'10
 Anchorage, AK 2010
- C-C. Lin, P. F. Nealey, T-H. Chang, Z. Ma, A. K. Raub, S. R. J. Brueck, E Han and P. Gopalan,
Integration of block copolymer directed self assembly with 193i lithography toward fabrication of nanowire MOSFETs
 SPIE Microlithography
 San Jose, CA 2011
- S.R.J. Brueck, Z. Ku and S. Smolev
Recent Progress in Fishnet Metamaterials at the University of New Mexico
 PIERS
 Marrakech, Morocco 2011
- S.R.J. Brueck, A. Neumann and Y. Kuznetsova
Imaging Inteferometric Microscopy
 PIERS
 Marrakech, Morocco 2011
- A. Neumann, Y. Kuznetsova and S. R. J. Brueck
Solid Immersion Imaging Interferometric Microscopy to the Limits of Available Frequency Space
 Focus on Microscopy, 2011
 Konstanz, Germany 2011
- Seung Chang Lee, S. Krishna and S. R. J. Brueck
Surface Plasma Wave Enhanced Infrared Detection (invited)
 Metamaterials 2011
 Barcelona, Spain 2011
- Keshav Dani, Zahyun Ku, Prasanth Upadhy, Rohit Prasankumar,
 S.R.J. Brueck and A.J. Taylor
Ultrafast Pump-Probe Spectroscopy of a Dual-Band Negative Index Metamaterial
 Metamaterials 2011
 Barcelona, Spain 2011

- Xiang He*, Stephen Benoit, R. Kaspi and S.R.J. Brueck
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